

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: S. KADLEC, et al.

Serial No: To be assigned

Filed: March 12, 2004

Title: METHOD FOR MANUFACTURING SPUTTER-COATED  
SUBSTRATES, MAGNETRON SOURCE AND SPUTTERING  
CHAMBER WITH SUCH SOURCE

Group: n/a

Examiner: n/a

**PRELIMINARY AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

March 12, 2004

Sir:

The following amendments and remarks are submitted in the above-  
identified application at the time of filing.

Amendments to the Claims

Remarks are included following the amendments